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BKS	A2	4,885,614	12/5/1989	Furukawa	et al							
	A3	5,032,893	7/16/1991	Fitzgerald	l et al.			2				
	A4	5,084,411	1/28/1992	Laderman	et al.							
	A5	5,091,767	2/25/1992	Bean et al		•		_				
	5,156,995	/			***							
\bigvee	A7	5,256,550	10/26/1993	Laderman	ı et al.							
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15/15	C4	Akatsu et al., "W								surface		
1	C5	Belgal et al., "A Physics Sympos		_	ne Defect For	mation in (CMOS Dev	ices," <u>Inte</u>	nation	al Reliability		
	C6	Bulsara et al., "R GaAs," Applied		-	_	_	•		ase epi	taxy on		
	C7 Cullis et al., "Growth ripples upon strained SiGe epitaxial layers on Si and misfit dislocation interactions," Journal of Vacuum Science and Technology, A 12(4) (July/August 1994), pp. 1924-1931.											
1	C8	Currie et al., "Ca substrates," <u>Jour</u> 2279.										
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JSKS A8	5,323,031	6/21/1994	Shoji et al	l.							
A9	5,659,187	8/19/1997	Legoues e	et al.		/	ک				
A10	5,801,085	9/1/1998	Kim et al.								
All	5,810,924	9/22/1998	Legoues e	et al.							
AI2	5,828,114	10/27/1998	Kim et al.								
√ A13	5,937,274	8/10/1999	Kondow e	et al.							
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SKS C9	De Boeck et al., silicon by molec										
C10	Feenstra et al., " Applied Physics	-		_	•	/SiGe hete	rostructure	s," <u>Jo</u>	umal of		
CII	Fitzgerald et al., and Engineering			elaxed gradeo	d compositi	on semico	nductors,"	Mater	ials Science		
C12	Godbey et al., "A Applied Physics		-		-	tion of thir	layer und	oped s	ilicon,"		
C13	Gonzales et al., Engineering, B4			ces in step-gra	aded buffer	structures	" <u>Material</u>	s Scie	nce and		
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75/65	A14	6,576,532		6/10/2003	Jones et a	1.					
13/15	A15	US 200201856	86A	12/12/2002	Christian	sen et al.					·
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TSKS	C14	Gray et al., "Eff						ivity in Rel	axed GeSi	Films	," <u>Physical</u>
	C15	Ha et al., "Anor									
	C16	Knall et al., "Th GaAs on Si," <u>Jo</u>		_	-	_			-	locatio	ons from
V	C17	MacElwee et al Electron Device					n-Insulator	Transistor	s," <u>IEEE T</u> i	ransac	tions on
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	C19	Meshkinpour et Applied Physics					high electro	on mobility	r transis	tor,"		
	C20	Mica et al., "Cry Journal of Physi						fabrication	technol	ogy,"		
	C21	Momose et al., " integrated system	'Dislocation-fronts," <u>Applied P</u>	ee and lattice hysics Letter	-matched Si/ s, Vol. 79, N	GaP1-xNx/ o. 25 (Dece	/Si structure ember 17, 2	for photo 001), pp. 4	-electron	nic 53.		
V	C22	Mooney et al., " Physics Letters,	Scanning x-ray Vol. 79, No. 1	/ microtopog 5 (October 8	raphs of mist , 2001), pp. 2	fit dislocation 2363-2365.	ons at SiGe	/Si interfac	es," <u>Ap</u>	plied		
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SKS	C23	Mooney et al., "S Materials Science			eroepitaxy ar	nd High-Sp	eed Micros	electronics,	" <u>Annu</u>	al Review of				
1	C24	Mooney et al., " Society Symposi						Layers," <u>M</u>	aterials	Research				
	C25 Morris et al., "Structure property anisotropy in lattice-mismatched single heterostructures," <u>Journal of Applied Physics</u> , 71 (5) (March 1, 1992), pp. 2321-2327.													
	C26	Ohashi et al., "S Science, (2003),		islocation acc	cumulation in	uLSI cell	ls with STI	structure,"	Applie	d Surface				
V	C27	Rammohan et al. x/GaAs(001) het												
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	C29	Sleight et al., "S Electron Device					hallow Tre	nch Isolate	d SOI,	" IEEE		
	C30 Soh et al., "Relation Between Etch Pit Pairs And Pipeline Defects In CMOS Device," International Reliability Physics Symposium, pp. 244-248.											
	C31 Su et al., "Effects of Dislocation and Bulk Micro Defects on Device Leakage," SEMICON Taiwan 2001, pp. 1-4.											
1	C32 Thompson et al., "NMOS Device Characteristics in Electron-Beam-Recrystallized SOI," <u>IEEE Transactions on Electron Devices</u> , Vol. 40, No. 7 (July 1993), pp. 1270-1276.											
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	C34	Wang et al., "PI					S CAUSEI	BY SWA	MI IS	OLATION,"	
	C35	Williams et al., ' Technologies, 20			• •						
	C36	Wu, "Novel Etcl Institute of Tech		ls for Silicor	Micromachi	ning," Ma	ster of Scie	nce Thesis,	Mass	achusetts	
V	C37 Yamada et al., "Static analysis of off-axis crystal film growth onto a lattice-mismatched substrate," Applied Physics Letters, Vol. 19, No. 5 (July 30, 2001), pp. 608-610.										
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BKS	C1	Nabarro, <u>Theory</u>	of Crystal Dis	locations (19	967) pp. 33.			•	•		
	C2 Houghton, "Strain relaxation kinetics in Si _{1-x} Ge _x /Si heterostructures," <u>J. Appl. Phys.</u> , Vol. 70, No. 4 (August 15, 1991) pp. 2136-2151.										
4	СЗ	Bruel et al., "®" International SO	SMART CUT I Conference (": A Promis October 199	ing New SOI 5) pp. 178-17	Material 7 79.	rechnology	," <u>178 Pro</u>	ceedin	es 1995 IEE	
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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

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ASC-061

APPLICANTS:

Lochtefeld et al.

SERIAL NO.:

10/629,498

FILING DATE:

July 29, 2003

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Kl.5	A16	5,357,119	10/1994		Wang et	et al.			_		
7	A17	5,668,387	09/1997	!	Streit et a	al.			_		
	A18	5,844,260	12/1998	(Ohori				_		
	A19	6,037,615	03/2000	Matsuyaı	ma et al.						
	A20	2003/0227057	12/2003	I	Lochtefe	ld et al.		J		10/2	002
	A21	2004/0005740	01/2004	I	ochtefe	ld et al.			<u>ر</u>	06/2	003
V	A22	2004/0031979	02/2004	I	ochtefe	ld et al.				06/2	003
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